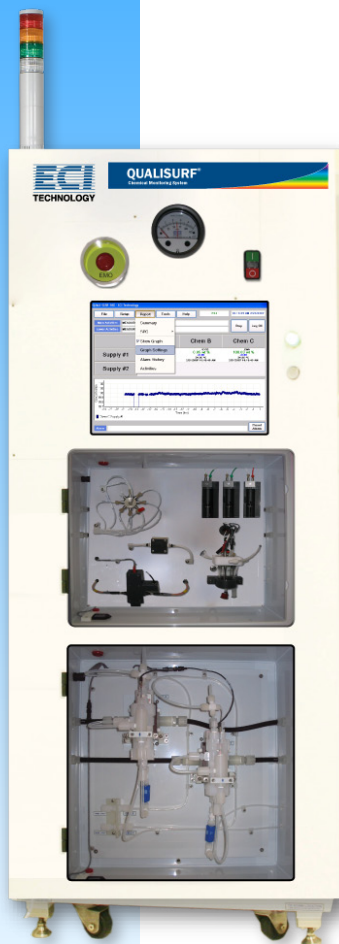


Take Control of Your Clean and Etch

Real-time Precise Analysis of Multiple-Component Clean/Etch solutions used in Semiconductor, FPD, LED and Solar Industries



QualiSurf is a high-end real-time NIR analyzer for precise monitoring of multiple-component chemistries. The QualiSurf enables users to maintain the concentrations and ratios of chemical components in wet processing solutions, preventing costly yield losses due to non-optimal chemistry. The same hardware can support numerous challenging applications by using various analytical models, such as: **SC1, SC2, SPM, BOE, DHF, Hot Phosphoric, DSP+, ST-250, CMP slurries, KOH/IPA, HF/HNO₃** and many other chemical mixtures used in the Semiconductor, FPD, LED and Solar industries. The analyzer provides instantaneous results which can be transmitted via closed-loop feedback to any single wafer or batch type cleaning tool, to maintain consistent concentrations and etch rates.

QualiSurf's flow-through analytical cell is integrated into the solution piping, eliminating cross contamination. Light is transmitted through the solutions and the resulting spectrum is collected by our proprietary detector. A unique ultra-low noise spectrometer combined with ECI's proprietary MVA algorithms allow differentiation of even the slightest concentration change in difficult ambiances such as temperature fluctuations, bubbles, and hot solutions. ECI also designed a high end multiplexer to allow monitoring of up to multiple different channels with a single tool, thus providing significant cost savings for the user.

QualiSurf™

Differentiating Even The Slightest Concentration Changes



We Keep The Chemistry Right.



QualiSurf

A real time non-invasive monitor for wet processing - measuring concentrations and process performance - that is QualiSurf!

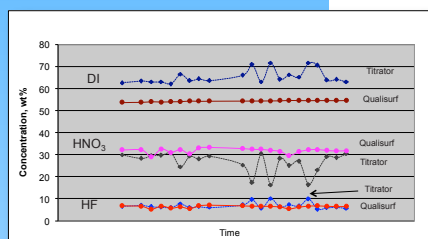
Features and Benefits

- Reporting individual concentrations of multiple-component chemistries
- Superior accuracy and precision
- Etch rate monitoring capability
- Multi-channel capable of controlling up to multiple different baths
- Real-time analyses and continuous monitoring of solutions
- In-line optics probe for incorporation with existing piping of wet processing equipment
- Feedback signals for automatic closed loop control of the process equipment
- Minimal PM requirements
- Built-in temperature compensation

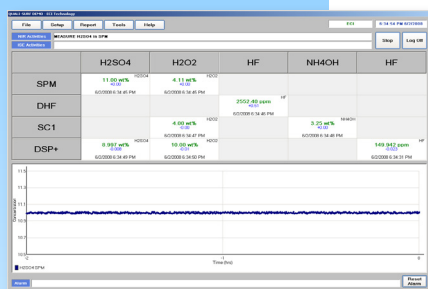
- Proprietary hardware/software combination eliminates and compensates for bubbles in sampling lines

Typical Applications

- Monitoring consistencies of wet processing/surface preparation solutions as the chemicals age
- Controlling point-of-use fresh chemical mixtures
- QualiSurf can be used to predict thin film etch rates of solutions
 - with extensive fab-proven results
- In-line monitoring of particle density in CMP slurries



QSF vs. Titrator
Customer Data



QualiSurf Screenshot

Semiconductor		Photovoltaic Solar Cell	
Cleaning	CMP	Si Texturing, PSG Removal and Edge Isolation	Cleaning
SPM	Particle Density	HF	HF/HCl
DSP, DSP+	Oxidant Concentration	HF/H ₂ SiF ₆	
SC1, SC2		HF/HNO ₃ /H ₂ SiF ₆	
BHF		HF/H ₂ SO ₄ /HNO ₃ /H ₂ SiF ₆	HF
DHF		HF/HNO ₃ /H ₂ SiF ₆ /proprietary acid	
TMAH	Copper Contamination	KOH	KOH
TMAH/H ₂ O ₂ /cleaner		KOH/K ₂ SiO ₃	
HF/HNO ₃		KOH/IPA/K ₂ SiO ₃	
ST-250	Particle Conglomerates	NaOH/Proprietary Cleaner/Na ₂ SiO ₃	
Proprietary Cleaners		NaOH/ Na ₂ SiO ₃	
Acid mixture for Metal Etch and Electropolishing			
MEA/BDG Stripper			

ECI will develop applications for customers to analyze proprietary solutions.

Backed by ECI Global Support

For additional information, call or write:
 ECI TECHNOLOGY, INC.
 60 Gordon Drive, Totowa, NJ 07512 U.S.A.
 Tel: 973-890-1114 Fax: 973-890-1118
 email: info@ecitechnology.com
 web site: www.ecitechnology.com
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